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520.34692V17

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: SORAOKA et al
Serial No.: 10/826,386
Filed: April 19, 2004
For: Vacuum Processing Apparatus And Semiconductor
Manufacturing Line Using The Same
Group: 3652
Examiner: T. Brahan

INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR 1.97 & 1.98

Mail Stop: DD
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

July 7, 2004

Sir:

In the matter of the above-identified application, applicants are submitting herewith a copy of the documents listed in the attached form equivalent to Form PTO-1449 for the Examiner's consideration.

This information disclosure statement is being submitted within three months of the filing date.

Each of the documents listed on the attached form equivalent to Form PTO-1449 is in the English language.

It is respectfully requested that this information disclosure statement be considered by the Examiner.

Please charge any shortage in the fees due in connection with the filing of this paper, including extension of time fees, to the deposit account of Antonelli, Terry,

Stout & Kraus, LLP, Deposit Account No. 01-2135 (Case: 520.34692V17), and
please credit any excess fees to such deposit account.

Respectfully submitted,

ANTONELLI, TERRY, STOUT & KRAUS, LLP



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Attachments

